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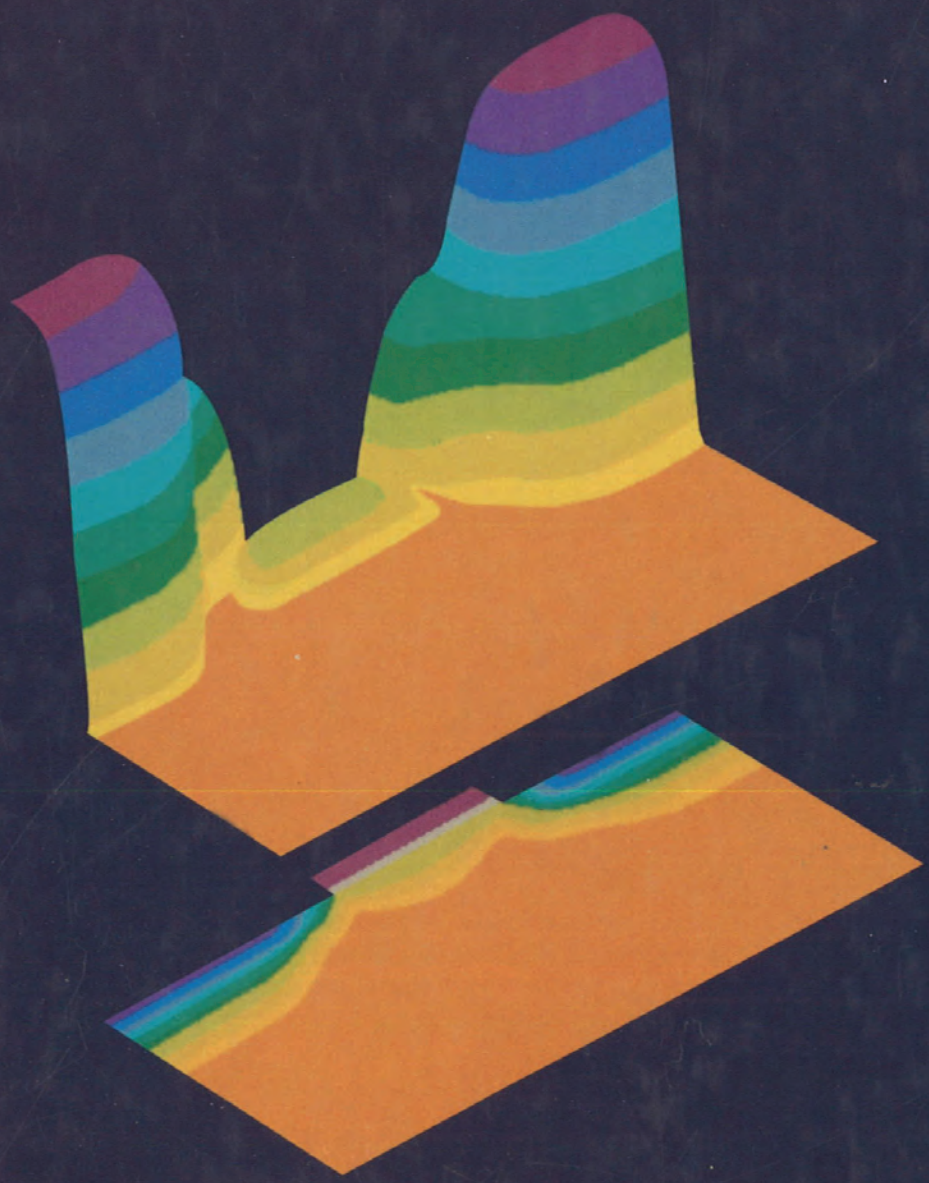

S. Wolf

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By STANLEY WOLF and RICHARD N. TAUBER

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1986 LATTICE PRESS 660 pp. ISBN 0-9616721-3-7

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Volume 3

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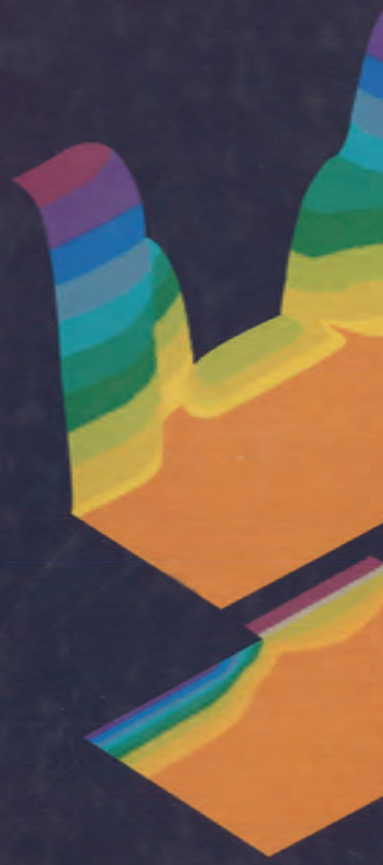

S. W

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FOR

THE VLSI ERA

VOLUME 3:

THE SUBMICRON MOSFET

STANLEY WOLF Ph.D.
Professor, Department of Electrical Engineering
California State University, Long Beach
Long Beach, California

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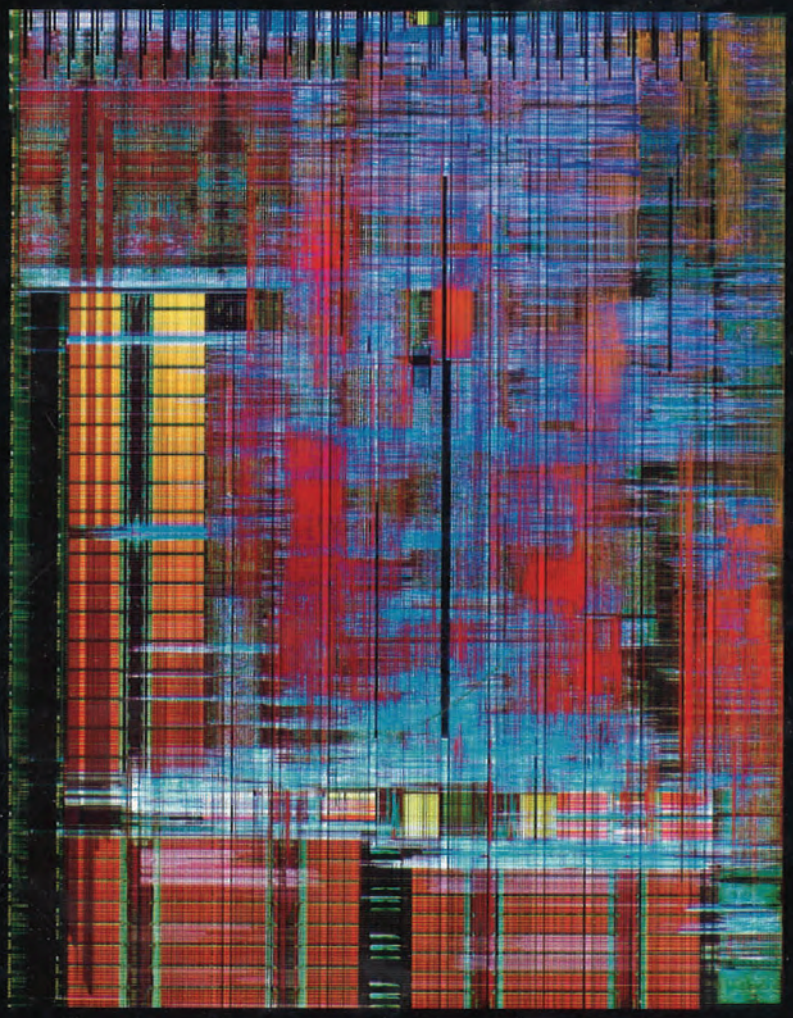

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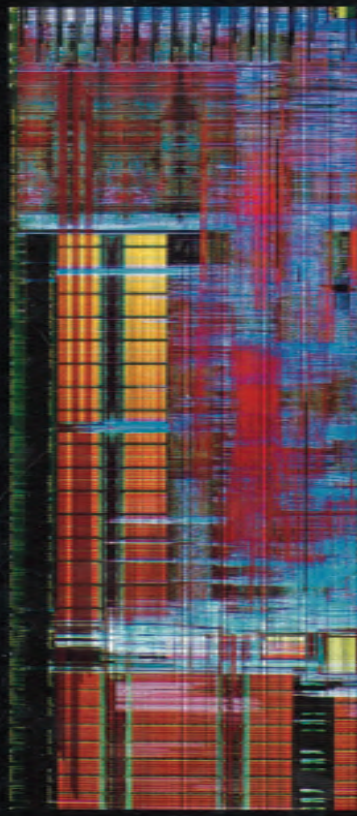

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